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Supporting information for article:

CBED Tools for semi-automatic measurement of crystal thicknesses

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Supplementary information

Figure 1 The result of the thickness determination of CBED pattern (d_{220}=1.918 A, 2α=6.86 mrad): t=201.3 nm, ξ_g=95.67 nm; the overlaid pattern is a simulated one with t=201 nm and 2α=6.86 mrad.
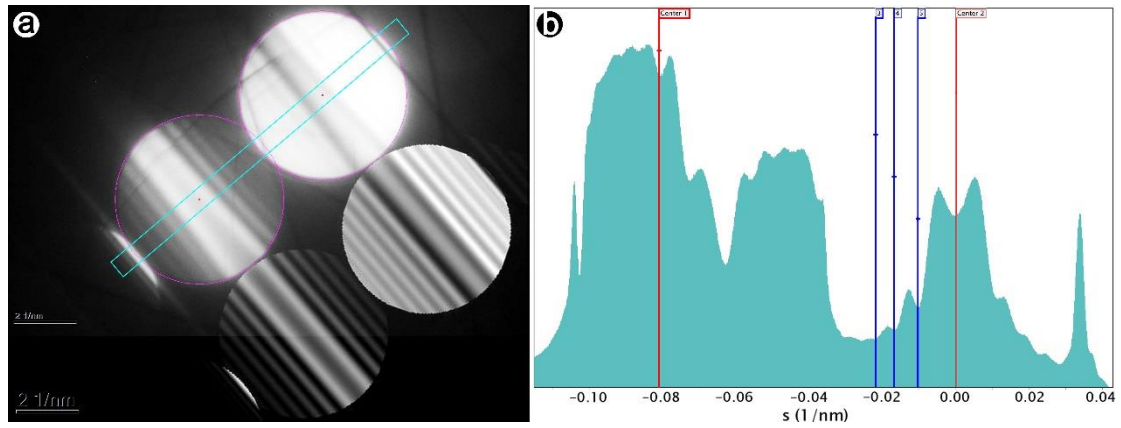

Figure 2 The result of the thickness determination of CBED pattern (d_{220}=1.889 A, 2α=6.78 mrad): t=236.2 nm, ξ_g=96.6 nm; the overlaid pattern is a simulated one with t=236 nm and 2α=6.78 mrad.

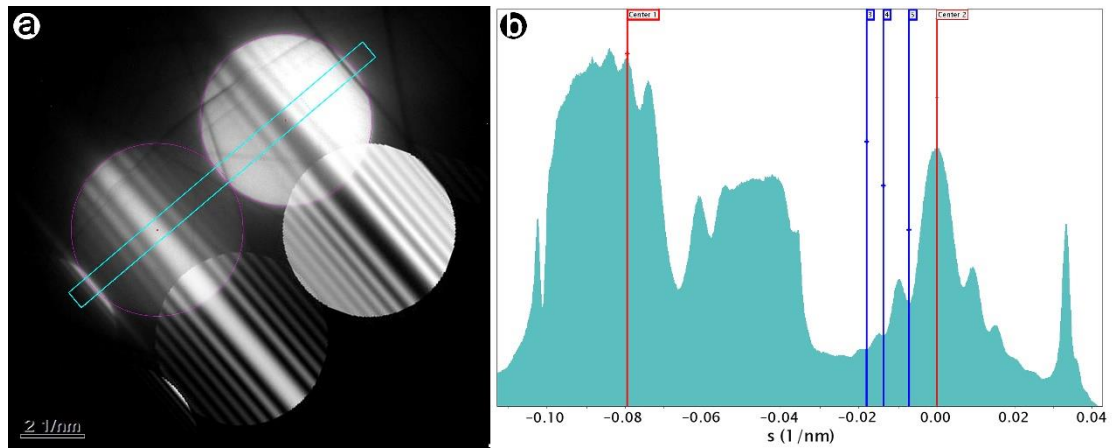Figure 3   The result of the thickness determination of CBED pattern (d$_{220}$=1.887 A, 2α=6.80 mrad): t=337.5 nm, ξ_g=93.0 nm; the overlaid pattern is a simulated one with t=337 nm and 2α=6.80 mrad.
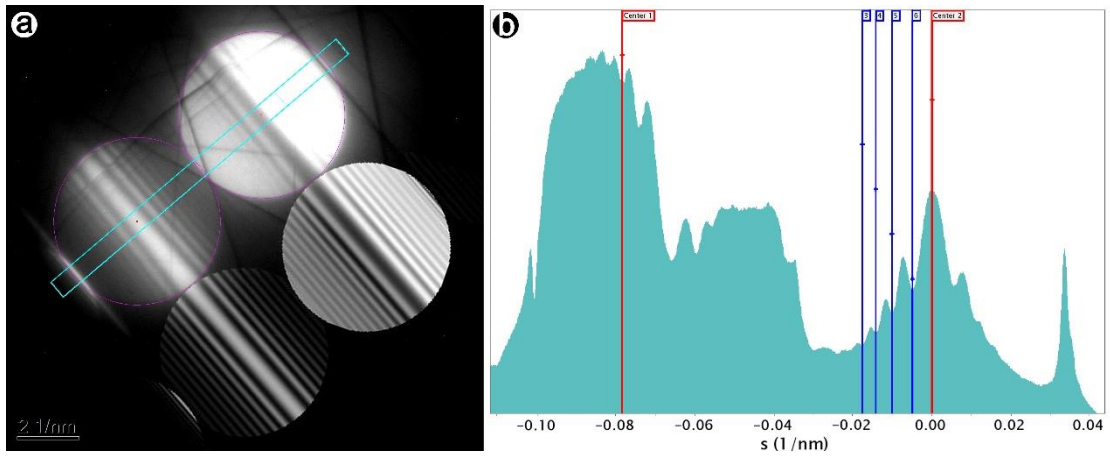
Figure 4   The result of the thickness determination of CBED pattern (d$_{220}$=1.905 A, 2α=6.82 mrad): t=424.5 nm, ξ_g=93.0 nm; the overlaid pattern is a simulated one with t=424 nm and 2α=6.82 mrad.
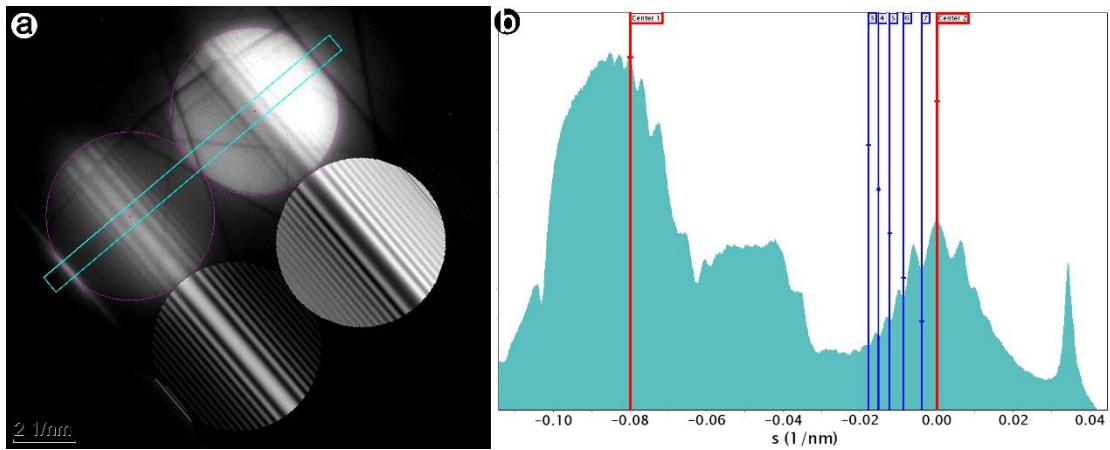
Table 1　The list of the parameters of the 16 random measurements of the CBED pattern in Fig. 1a: Bragg angle $2\theta_B$, thickness t and the extinction distance ξ_g.

No.	$2\theta_B$ (pix)	t (nm)	ξ_g (nm)
1	965	200.281	98.7424
2	966	199.353	98.4555
3	967	200.127	98.7687
4	969	200.744	98.1786
5	969	200.547	98.3437
6	965	198.745	98.7907
7	966	199.877	98.0805
8	968	200.482	98.7431
9	968	200.222	99.0467
10	967	200.546	99.0416
11	965	199.837	99.0973
12	966	200.29	98.9824
13	967	200.327	98.711
14	967	200.359	98.6447
15	966	199.906	98.7561
16	967	200.754	98.3106